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PATENT

UNITED STATES PATENT AND TRADEMARK OFFICE

Application of Fuerhoff et al.

Serial No. 09/502,340

Filed February 10, 2000

For METHOD AND APPARATUS FOR CONTROLLING DIAMETER OF A SILICON
CRYSTAL IN A LOCKED SEED LIFT GROWTH PROCESS

April 28, 2000

TO THE COMMISSIONER OF PATENTS AND TRADEMARKS,

SIR:

INFORMATION DISCLOSURE STATEMENT

In accordance with 37 C.F.R. 1.97 and 1.98 and MPEP 609, and in compliance with the duty
of disclosure set forth in 37 C.F.R. 1.56, applicants submit copies of the references listed on the
attached PTO Form 1449 (modified) for consideration by the Patent and Trademark Office in the
above-entitled application and to be made of record herein.

Respectfully submitted,

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CERTIFICATE OF MAILING

I certify that this Letter to the Patent and Trademark Office and attached PTO Form 1449 is
being deposited with the United States Postal Service as first class mail, postage prepaid, in an
envelope addressed to: Assistant Commissioner for Patents, Washington, D.C. 20231 on this 28th
day of April, 2000.

C. Jonell Layton, PLS

RMB/cjl
Attachments